



INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

Docket Number (Optional)
KLAC0075

Application No.
10/615,512

Applicant
Yung-Ho Chuang, et al.

Filing Date
July 7, 2003

Group Art Unit
2872

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
LF	2 6 6 1 6 5 8	12/1953	Dyson			
	1 9 7 3 0 6 6	9/1934	Hauser et al.			
	4 9 7 4 0 9 4	11/1990	Morito			
	4 7 5 8 0 8 8	7/1988 7/19/1988	Doyle			
	5 1 7 7 5 5 9	1/1993	Batchelder et al.			
	4 8 9 8 4 7 1	2/1990	Stenstrom et al. Vaught, et al.			
	5 4 2 8 4 4 2	6/1995	Lin et al.			
	5 0 3 1 9 7 6	7/1991	Shafer			
	5 7 1 7 5 1 8	2/1998	Shafer et al.			
	5 6 4 4 1 4 0	7/1997	Biedermann et al.			
	5 4 8 8 2 2 9	1/1996	Elliott et al.			
	3 2 3 7 5 1 5	3/1966	Altman			
LF	5 7 1 7 5 1 8	2/1998	Chuang			

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FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
LF	3 7 4 2 8 0 6	7/1989	DE				
LF	9 7 1 2 2 2 6	4/1997	WO				
LF	1 0 8 1 8 1	1/1900	DE				
LF	2 2 6 9 0 2 4	1/1994	GB				
LF	0 7 9 8 5 8 5	10/1997	EP				

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

LF	M.R. Bartz et al., "LED Print Analyzer," IBM Technical Disclosure Bulletin, Vol 14, No. 3, 8/1971
LF	D.S. Goodman, "Darkfield Illuminator Attachment," IBM Technical Disclosure Bulletin, Vol. 27, No. 5, 10/1984
LF	J.L.C. Sanz et al., "Automated Visual Inspection with Dark-Field Microscopy," Journal of the Optical Society of America, November 1985, USA, Vol. 2, No. 11, pp. 1857-1862
LF	Carl Zeiss Brochure, "MSM 193 Microlithography Simulation Microscope," 1999

EXAMINER /Lee Fineman/

DATE CONSIDERED 10/30/2006

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP §609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.